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Application Number	09/920,341				
Filing Dat	August 1, 2001				
First Named Inventor	Choi et al.				
Group Art Unit	1732				
Examiner Name	Tentoni, Leo B.				
Attorney Docket Number	UTS-17-07V06				

				U.S. PATENT DOCUMENTS							
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OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS							
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Form PTO-1449 (modified) ATTY. DKT. NO. 5119-08301 SERIAL NO. 09/920,341 List of Patents and Publications PFe Applicant's Information APPLICANT: Choi et al. **GROUP: 1724** Disclosure Statement se several sheets if necessary) FILING DATE: August 1, 2001 U.S. PATENT DOCUMENTS FILING DATE IF APPROPRIATE EXAM. DOCUMENT NUMBER DATE NAME **CLASS** SUB ALPHDEM'S DES. **CLASS** 4/1974 3,807,027 Heisler A1 A2 3,807,029 4/1974 Troeger 5/1974 **A3** 3,811,665 Seelig **A4** 4,062,600 12/1977 Wyse Α5 4,098,001 7/1978 Watson **A6** 4,155,169 5/1979 Drake et al. Watson **A7** 4,202,107 5/1980 A8 Sakawaki 4,267,212 5/1981 Α9 7/1982 De Fazio 4,337,579 A10 4,355,469 10/1982 Nevins et al. De Fazio A11 4,414,750 11/1983 A12 5/1984 Beltz et al. 4,451,507 A13 4,610,442 9/1986 Oku et al. 沿 A14 4,694,703 11/1987 Routson TH 4,731,155 A15 3/1988 Napoli et al. A16 4,763,886 8/1988 Takei A17 4,929,083 5/1990 Brunner A18 4,959,252 11/1990 Bonnebat et al. A19 5,072,126 12/1991 Progler A20 5/1992 5,110,514 Soane A21 5,126,006 6/1992 Cronin et al. A22 5,204,739 4/1993 Domenicali A23 8/1993 Boehnke et al. 5,240,550 A24 9/1994 5,348,616 Hartman et al. A25 5,392,123 2/1995 Marcus et al. Southwell et al. A26 5,425,964 6/1995 A27 9/1995 SN 5,452,090 Progler et al.

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APPLICANT: Choi et al.

SERIAL NO. 09/920,341

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